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Docket No. MIT7941

1763

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE****Applicants: Yong-Pil Han et al.****Serial No.: 09/498,303****Filed: February 4, 2000****For: HF Vapor Phase Wafer Cleaning and Oxide Etching****Confirmation No. 8629****Group Art Unit: 1763****Examiner: T. Dang**RECEIVED  
DEC 04 2003  
TC 1700**COMMISSIONER FOR PATENTS****P. O. BOX 1450****ALEXANDRIA, VIRGINIA 22313-1450**

I hereby certify that this correspondence is being deposited on the date shown below with the United States Postal Service with sufficient postage as first class mail, under 37 CFR 1.8(a), in an envelope addressed to: Commissioner For Patents, Alexandria, VA 22313-1450

*Theresa A. Lober*  
November 20, 2003

**PETITION FOR THREE -MONTH EXTENSION OF TIME UNDER 37 C.F.R. 1.136(a)**

Hereby is petitioned the Assistant Commissioner for Patents to extend for the patent application referenced above the period for response to the Examiner's Action mailed May 21, 2003, for three (3) months, extending the last day of the response period from August 21, 2003, up to and including November 21, 2003.

A response to the Examiner's Action is being filed on even date herewith.

Please apply the extension fee of \$475.00 under 1.17(a)(3) to Deposit Account No. 19-2553. Please apply any deficiency in the stated fee and any other required fees, and please apply any overpayment, to Deposit Account No. 19-2553.

12/01/2003 LWDNDIM1 00000050 192553 09498303

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Date

Nov. 20, 2003

Respectfully submitted,

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